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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Julia S. Svirchevski et al.

Application No. 09/336,041⁴⁰¹

Filed: June 18, 1999

For: POST-PLASMA PROCESSING WAFER
CLEANING METHOD AND SYSTEM



) Docket No: LAM1P109
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) Group Art Unit: 1765
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) Examiner: L. Umez-Eronini
)
) Date: December 5, 2000
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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, DC 20231 on December 5, 2000.

Signed:

Diane Schwanbeck

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Sir:

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